

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Mamoru Nakasuji, et al.**

Serial No.: **Not yet assigned**

Filed: **January 29, 2004**

For: **ELECTRON BEAM APPARATUS AND METHOD OF
MANUFACTURING SEMICONDUCTOR DEVICE USING THE
APPARATUS**

Attorney Docket No.: 011470A

Customer Number: **38834**

INFORMATION DISCLOSURE STATEMENT PURSUANT TO 37 CFR §1.97(b)

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

January 29, 2004

Sir:

This Information Disclosure Statement is being filed in order to comply with Applicant's duty of disclosure under 37 C.F.R. §1.56. The documents listed on the Form PTO/SB/08 were made of record in parent application Serial No. 09/985,322.

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Respectfully Submitted,

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Sheet 1 of 2

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Application Number	to be assigned
Filing Date	January 29, 2004
First Named Inventor	M. Nakasuji
Art Unit	to be assigned
Examiner Name	to be assigned
Attorney Docket Number	011470A

U. S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US- 6,125,522	10/3/00	Nakasuji	
		US- 6,087,667	7/11/00	Nakasuji, et al.	
		US- 5,981,947	11/9/99	Nakasuji, et al.	
		US- 5,892,224	4/6/99	Nakasuji	
		US- 5,359,197	10/25/94	Komatsu, et al.	
		US- 4,912,052	3/27/90	Miyoshi, et al.	
		US- 4,726,689	2/23/88	Pollock	
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FOREIGN PATENT DOCUMENTS

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Sheet	2	of	2	Applicant Number	to be assigned
				Filing Date	January 29, 2004
				First Named Inventor	M. Nakasuji
				Art Unit	to be assigned
				Examiner Name	to be assigned
				Attorney Docket Number	011470A

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
	1	Sandland; "An Electron-beam inspection system for x-ray mask production", J. of Vacuum Sci & Tech.B (1991) Vol. 9, No. 6; pp3005-3009	
	2	Meisburger et al; "Requirements and performance of an electron-beam column designed for x-ray mask inspection"; J. of Vacuum Sci & Tech.B (1991) Vol. 9, No. 6; pp 3010-3014	
	3	Lischke et al; "Multi-beam concepts for Nanometer Devices"; JP J. Applied Physics (1989) Vol. 28, pp 2058-64.	
	4	Electron/Ion Beam Handbook 2nd; Nikkan Kogyo (1988) pp 115-119 (with partial English Translation).	
	5	U.S. Patent Application S.N. 09/985,323; filed 11/2/2001; Mamoru Nakasuji et al; "Electron Beam Apparatus and Device Production Method Using the Electron Beam Apparatus"	
	6	U.S. Patent Application S.N. 09/985,324; filed 11/2/2001; Toshifumi Kimba et al; "Apparatus for Inspecting Material with Electron Beam, Method for Operating Same, and ...	
	7	U.S. Patent Application S.N. 09/985,325; filed 11/2/2001; Mamoru Nakasuji et al; "Electron Beam Apparatus and Method of Manufacturing Semiconductor Device Using the ..."	
	8	U.S. Patent Application S.N. 09/985,331; filed 11/2/2001; Mamoru Nakasuji et al; "Method for Inspecting Substrate, Substrate Inspecting System and Electron Beam Apparatus"	

Examiner Signature	Date Considered
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